

Abstract**Method of Cleaving GaN/Sapphire for Forming Laser Mirror Facets**

5 A method of fabricating a cleaved facet of a laser device having a substrate and at least one GaN-based layer formed upon a first surface of the substrate, said method including the following steps:

10 • cutting linear grooves into a second surface of the substrate, said grooves being in alignment with vertical planes of said substrate; and

 • cleaving said substrate and said at least one GaN-based layer along said vertical planes;

 wherein said cutting is effected by a laser beam from an external laser source.